## Amendments to the Claims:

## Listing of Claims:

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Claim 1 (original) A flash memory cell structure comprising:

- a substrate having a stacked gate;
- a select gate formed on the substrate and adjacent to one side of the stacked gate;
  - a first-type doped region located in the substrate and adjacent to the select gate as a drain;
- a shallow second-type doped region located underneath the stacked gate and adjacent to the first-type doped region;
  - a deep second-type doped region surrounding the first-type doped region and adjacent to the shallow second-type doped region; and
  - a doped source region formed on a side of the shallow second-type doped region as a source.

Claim 2 (original) The flash memory cell structure of claim 1 wherein a depth of the deep second-type doped region is deeper than a depth of the shallow second-type doped region.

- Claim 3 (original) The flash memory cell structure of claim 1 wherein the deep second-type doped region has the same doped ions as the shallow second-type doped region.
- Claim 4 (original) The flash memory cell structure of claim 3 wherein the doped ions of the deep second-type doped region and the shallow second-type doped region are selected from the III A group.

Claim 5 (original) The flash memory cell structure of claim 1 wherein the

doped ions of the first-type doped region and the doped source region are selected from the V A group.

Claim 6 (original) The flash memory cell structure of claim 1 wherein the first-type doped region and the deep second-type doped region are electrically short-circuited together.

Claim 7 (original) The flash memory cell structure of claim 6 wherein the first-type doped region and the deep second-type doped region are electrically short-circuited by metal penetrating the junction between the first-type doped region and the deep second-type doped region.

Claim 8 (original) The flash memory cell structure of claim 6 wherein the first-type doped region and the deep second-type doped region are electrically short-circuited by metal exposed outside the first-type doped region and the deep second-type doped region of the substrate.

Claim 9 (original) The flash memory cell structure of claim 1 wherein the stacked gate includes a floating gate located over the shallow second-type doped region, and a control gate located over the floating gate.

Claims 10-16 (cancelled)

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Claim 17 (new) A flash memory cell structure comprising:

- 25 a substrate having a stacked gate;
  - a select gate formed on the substrate and adjacent to one side of the stacked gate, the select gate being able to prevent an edge program

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disturb issue and an over program problem;

- a first-type doped region located in the substrate and adjacent to the select gate as a drain;
- a shallow second-type doped region located underneath the stacked gate and adjacent to the first-type doped region;
- a deep second-type doped region surrounding the first-type doped region and adjacent to the shallow second-type doped region; and
- a doped source region formed on a side of the shallow second-type doped region as a source.

Claim 18 (new) The flash memory cell structure of claim 17 wherein a depth of the deep second-type doped region is deeper than a depth of the shallow second-type doped region.

Claim 19 (new) The flash memory cell structure of claim 17 wherein the deep second-type doped region has the same doped ions as the shallow second-type doped region.

Claim 20 (new) The flash memory cell structure of claim 19 wherein the doped ions of the deep second-type doped region and the shallow second-type doped region are selected from the III A group.

Claim 21 (new) The flash memory cell structure of claim 17 wherein the doped ions of the first-type doped region and the doped source region are selected from the V A group.

Claim 22 (new) The flash memory cell structure of claim 17 wherein the first-type doped region and the deep second-type doped region are

electrically short-circuited together.

Claim 23 (new) The flash memory cell structure of claim 22 wherein the first-type doped region and the deep second-type doped region are electrically short-circuited by metal penetrating the junction between the first-type doped region and the deep second-type doped region.

Claim 24 (new) The flash memory cell structure of claim 22 wherein the first-type doped region and the deep second-type doped region are electrically short-circuited by metal exposed outside the first-type doped region and the deep second-type doped region of the substrate.

Claim 25 (new) The flash memory cell structure of claim 17 wherein the stacked gate includes a floating gate located over the shallow second-type doped region, and a control gate located over the floating gate.